EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1431	427/585.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/06/17 13:21
L2	1	427/585.ccls. and (atomic force microscope or AFM or SPM or tip) and electromagnetic with "near" field	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/06/17 13:22
L3	2	427/585.ccls. and (atomic force microscope or AFM or SPM or tip) and plasmon	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/06/17 13:24
L4	153	427/585.ccls. and (CVD or chemical vapor deposition) with (light or radiat$3 or irradiat$3 or laser)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/06/17 13:25
L5	29	427/585.ccls. and (CVD or chemical vapor deposition) with (light or radiat$3 or irradiat$3 or laser) and (atomic force microscope or AFM or SPM or tip)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/06/17 13:26
L6	2	427/585.ccls. and (CVD or chemical vapor deposition) with (light or radiat$3 or irradiat$3 or laser) and (atomic force microscope or AFM or SPM or tip).ab.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/06/17 13:26
S1	1	("7315367").PN.	USPAT; USOCR	OR	OFF	2009/12/09 12:45
S2	4	("20050046832" | "6313905").PN.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 12:46
S3	4	("4550257" | "4550257" | "5294465" | "5294465").PN.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 13:52

S4	4426	427/248.1.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 14:55
S5	605	427/582-584.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 14:57
S6	44957	(AFM or STM or atomic force microscop$2 or scanning tunneling or SFM or scanning force microscop$2)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 14:59
S7	5	S5 and S6	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 14:59
S8	117	S4 and S6	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 15:41
S9	153	(AFM or STM or atomic force microscop$2 or scanning tunneling or SFM or scanning force microscop$2) with (vapor or vapour) deposition	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 15:42
S10	117	S4 and S8	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 15:42
S11	59141	(AFM or STM or atomic force microscop$2 or scanning tunneling or SFM or scanning force microscop$2 or probe tip)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 17:43
S12	605	427/582-584.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 17:44
S13	7	S12 and S11	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 17:44

S14	4	FOLANT	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/09 17:45
S15	2	("2002/0105641").URPN.	USPAT	ADJ	ON	2009/12/09 17:46
S16	16	("4343993" | "4539089" | "4550257" | "4605566").PN. OR ("5294465").URPN.	US-PGPUB; USPAT; USOCR	ADJ	ON	2009/12/09 17:47
S17	18	hybrid with afm with stm	US-PGPUB; USPAT; USOCR	ADJ	ON	2009/12/09 17:53
S18	15	metallized with AFM with probe	US-PGPUB; USPAT; USOCR	ADJ	ON	2009/12/09 17:54
S19	1	("4539089").PN.	USPAT; USOCR	OR	OFF	2009/12/10 11:20
S20	1544892	(AFM or STM or atomic force microscop$2 or scanning tunneling or SFM or scanning force microscop$2 or probe or tip)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 11:27
S21	0	focus$3 with nearfield with tip	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 11:41
S22	1066	focus$3 with laser with tip	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 11:41
S23	1066	focus$3 with tip with laser	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 11:42
S24	2967	focus$3 same tip same laser	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 11:42
S25	269	focus$3 same tip same laser and (cvd or vapor deposition or vapour deposition)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 11:43
S26	15	focus$3 same tip same laser same (cvd or vapor deposition or vapour deposition)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 11:43

S27	89	multiple with tip with afm	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 14:09
S28	0	parallel process$3 with tip with afm	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 14:14
S29	0	parallel process$3 with afm	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 14:15
S30	562	parallel with afm	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 14:15
S31	30	parallel with afm and multiple tip	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/10 14:15
S32	266	(AFM or atomic force microscop$2) with (probe or tip) and (CVD or chemical vapor deposition) with (light or radiat$3 or irradiat$3 or laser)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/16 10:18
S33	8	(AFM or atomic force microscop$2) with (probe or tip) with (CVD or chemical vapor deposition) with (light or radiat$3 or irradiat$3 or laser)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/16 10:18
S34	101	(AFM or atomic force microscop$2) with (probe or tip) with (CVD or chemical vapor deposition)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/16 10:19
S35	86	((AFM or atomic force microscop$2) and (CVD or chemical vapor deposition)).ab.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/16 10:22
S36	88	((AFM or atomic force microscop$2 or SFM or scanning force microscop$2) and (CVD or chemical vapor deposition)).ab.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/16 10:23

S37	10	(AFM or atomic force microscop$2 or SFM or scanning force microscop $2) with (CVD or chemical vapor deposition) with (light or radiat$3 or irradiat $3 or laser)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/16 10:31
S39	2	977/849.ccls. and (CVD or chemical vapor deposition) with (light or radiat$3 or irradiat$3 or laser)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/12/16 10:47
S40	2	(("4550257") or ("5294465")).PN.	USPAT; USOCR	OR	OFF	2011/04/13 10:34
S41	164	977/849.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/04/13 12:01

EAST Search History (Interference)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L7	140	(CVD or vapor deposition) with (light or radiat$3 or irradiat$3 or laser) and (atomic force microscope or AFM or SPM or tip).ab.	USPAT; UPAD	ADJ	ON	2011/06/17 13:30
L8	0	(CVD or vapor deposition) with (light or radiat$3 or irradiat$3 or laser) with (atomic force microscope or AFM or SPM or tip).ab.	USPAT; UPAD	ADJ	ON	2011/06/17 13:31
L9	34	(CVD or vapor deposition) with (light or radiat$3 or irradiat$3 or laser) with (atomic force microscope or AFM or SPM or tip)	USPAT; UPAD	ADJ	ON	2011/06/17 13:31
L10	15	(CVD or vapor deposition) with (light or radiat$3 or irradiat$3 or laser).clm. and (atomic force microscope or AFM or SPM or tip).clm.	USPAT; UPAD	ADJ	ON	2011/06/17 13:34
L11	79	(CVD or vapor deposition).clm. and (light or radiat$3 or irradiat$3 or laser).clm. and (atomic force microscope or AFM or SPM or tip).clm.	USPAT; UPAD	ADJ	ON	2011/06/17 13:36

| L12 | 64 | (CVD or vapor deposition). clm. and (light or radiat$3 or irradiat$3 or laser).clm. and (atomic force microscope or AFM or SPM or tip).clm. not l10 | USPAT; UPAD | ADJ | | ON | 2011/06/17 13:36 |

6/17/2011 1:38:51 PM
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